

Notice of References CitedApplication No.
09/471,460Applicant(s)
Figura et al.Examiner
Calvin LeeGroup Art Unit
2825

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U.S. PATENT DOCUMENTS

*		DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS
	A	6,089,183	07/18/00	Imai et al.	118	723
	B	5,048,413	01/28/92	Fujita et al.	437	189
	C					
	D					
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	G					
	H					
	I					
	J					
	K					
	L					
	M					

FOREIGN PATENT DOCUMENTS

*		DOCUMENT NO.	DATE	COUNTRY	NAME	CLASS	SUBCLASS
	N						
	O						
	P						
	Q						
	R						
	S						
	T						

NON-PATENT DOCUMENTS

*		DOCUMENT (Including Author, Title, Source, and Pertinent Pages)	DATE
X	U	Ephrath, L. M., "Teflon Polymer Mask for RIE of Contact Roles", IBM Technical Disclosure Bulletin, Vol. 25, No. 9, pp. 4587-4588	FALSE
	V		
	W		
	X		

* A copy of this reference is not being furnished with this Office action.
(See Manual of Patent Examining Procedure, Section 707.05(a).)